Amendment to the Specification

Please replace the paragraph beginning on page 1, line 12, with the following amended paragraph:

A CVD system includes a diffuser for evenly distributing the reactant gases over a substrate. The diffuser is made of metal to serve as a powered electrode, and it is combined with a diffuser frame serving as an electrode extension by bolts. Since there is a gap between the diffuser and the diffuser frame, an arc may be generated in the gate when the diffuser 70 is supplied with high radio frequency power. The arc may remove oxide such as Al₂O₃ coated on the diffuser and the diffuser frame, and the metal forming the diffuser may be melted to be dropped on melt and drop onto the substrate. The dropped metal component generates splash defect defects to reduce the quality of deposited thin films.

Please replace the paragraph beginning on page 3, line 22, with the following amended paragraph:

A blocking member (or a backing member) 90 is located in front of the inhalation conduit 80a, and a diffuser 70 is disposed below the blocking member 90 with being and is spaced apart from the blocking member 90 by a predetermined distance.

Please replace the paragraph beginning on page 4, line 19, with the following amended paragraph:

The frame 70b extends under an insulating ceramic frame 5 provided for preventing arc generation between the chamber diffuser 70 and a chamber lid 20.

MacPherson Kwok Chen & Heid LLP 1762 Technology Drive, Suite 220 - San Jose, CA 95110 Telephone: (408) 392-9250 Facsimile: (408) 392-9262